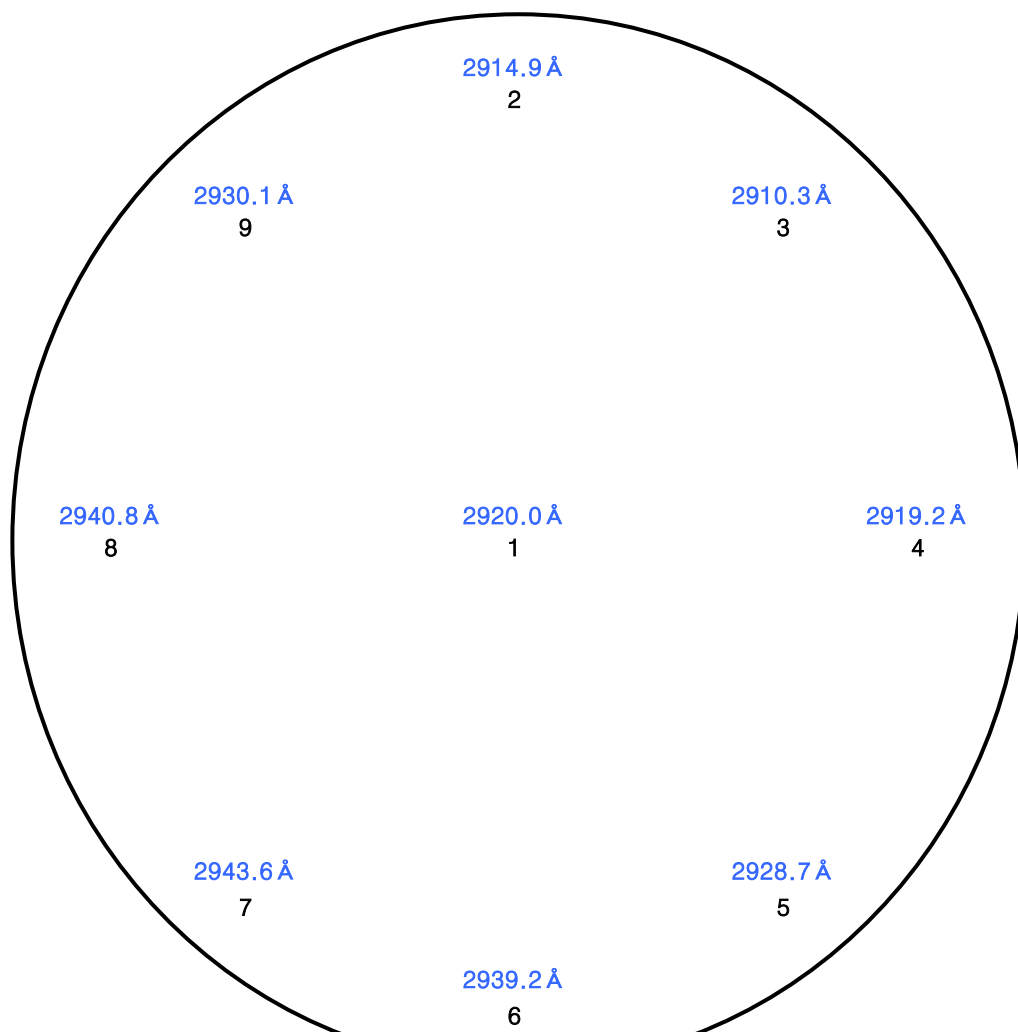


inspection report

wafer specification		Process order		measurement system
maker	ZING SEMI	Process	Wet oxidation	Nano-spec
diameter	299.8 – 300.2 mm	lot no.	702300F6321	Inspection date
thickness	750 – 800 um	type.	Double polished	2017-11-29
orientation	P – 100 (Boron)	material	SiO2 on Si	
resistivity	0.5 – 100 Ωcm	edge exclusion	≒ 5mm	



film information		
material	SiO2	index.
slot.	13	n/a
1	2920.0 Å	
2	2914.9 Å	
3	2910.3 Å	
4	2919.2 Å	
5	2928.7 Å	
6	2939.2 Å	
7	2943.6 Å	
8	2940.8 Å	
9	2930.1 Å	
max	2943.6 Å	
min	2910.3 Å	
Aver.	2927.4 Å	
uniform.(%)	0.57%	

	operator	inspector	approval	remark
signature	박민재	황의경		